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Attorney Docket # 5367-47

Patent

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Stefan BADER et al.

Serial No.: 10/696,882

Filed: October 30, 2003

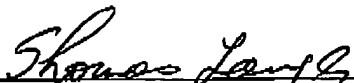
For: Method for Depositing a Material on a Substrate  
WaferExaminer:  
Group Art:I hereby certify that this correspondence is being  
facsimile transmitted to the United States Patent &  
Trademark Office on:December 14, 2005  
(Date of Transmission)(571) 273-8300  
Facsimile No.Thomas Langer  
Name of applicant, assignee or Registered Representative  
SignatureDecember 14, 2005  
Date of SignatureCommissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450STATUS LETTER

SIR:

In reviewing our file in the above-identified patent application, we note that we have received no action since the filing of this application on October 30, 2003. We would therefore appreciate a report as to the status of this case at your earliest possible convenience.

Respectfully submitted,  
COHEN, PONTANI, LIEBERMAN & PAVANE

By



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